The 7th International Conference on Microelectronics and Plasma Technology

ICMAP 2018

Joint International Conference on ICMAP 2018, APCPST 2018, and ISPB 2018

APCPST 2018 (Asia-Pacific Conference on Plasma Science and Technology) **ISPB 2018** (International Symposium of Plasma Biosciences 2018)

July 25-28, 2018 | Songdo ConvensiA, Incheon, Korea



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Welcome Message





The 7th International Conference on Microelectronics and Plasma Technology (ICMAP 2018) will be held during July 25-28, 2018 at Songdo ConvensiA, Incheon, Korea. This meeting will be held joint International conference on ICMAP 2018, APCPST 2018, and ISPB 2018. ICMAP 2018 is initiated to provide an open forum for the discussion of the current status of scientific and technological achievements in the various fields of plasma applied research and developments including microelectronic devices.

On behalf of the organizing committee, we would like to express my warmest welcome to all of you who are participating in ICMAP 2018. We hope that will provide a wonderful scientific and social program of the conference with your active participation. We are looking forward to seeing you at ICMAP 2018 in Incheon, Korea!



Organizing Committee

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Conference Topics

Plasma Bioscience / Plasma Agriculture / Plasma **Energy / Environmental Applications**

- Plasma Farming
- Plasma Biomedicine
- Plasma & Liquids
- Etc

Materials and Processing on Semiconductor / Display **Nano-Devices**

- Plasma ALD / PECVD
- Sputtering / Ion Beam Deposition
- Plasma for Nanomaterial Processing
- Next Generation Plasma Etching, Ashing, and Patterning
- Plasmas for Environmental Technology
- Etc

Basic Plasma Science, Technology, Engineering and **Related Topics**

- Plasma Assisted Process Monitoring Technologies
- Contamination control in Semiconductor / Display Technologies
- Plasma Sources and Technologies
- ESC Chuck
- Modeling and Simulation Techniques
- Fundamental Processes in Plasma
- Etc

Applications of Plasma Processing

- Nano Devices Using 2D Materials
- Sensors and Actuators
- Energy Related Devices
- Flexible / Stretchable Display Technology
- Etc

ICMAP 2018 Secretariat

273, Baeul 1-ro, Yuseong-gu, Daejeon, Korea 34036

TEL +82-42-472-7461 / FAX +82-42-472-7459 / E-MAIL office@icmap-2018.org / www.icmap-2018.org